

**Current Status of All Claims in the Application:**

1. (Currently Amended) A fluid mount comprising:  
a first subsystem including a first cylinder and a first piston, the first piston moving within the first cylinder and cooperating with the first cylinder to define a first chamber; and  
a second subsystem including a second cylinder and a second piston, the second piston moving within the second cylinder, ~~the second piston moving concurrently with the first piston.~~ and cooperating with the second cylinder to define a second chamber;  
an intermediate chamber positioned between the first chamber and the second chamber; and  
a control system that is connected to the intermediate chamber, the control system actively adjusting a pressure inside the intermediate chamber to be below the lower one of a pressure inside the first chamber and a pressure inside the second chamber.
2. (Original) The fluid mount of claim 1 wherein the first piston moves along a first axis and the second piston moves along a second axis that is substantially coaxial with the first axis.
3. (Currently Amended) The fluid mount of claim 1 further comprising a piston connector that couples the first piston ~~and~~ to the second piston so that the first piston and the second piston move concurrently.
4. (Currently Amended) The fluid mount of claim ~~[[4]]~~ 3 wherein the piston connector extends around the second cylinder.
5. (Original) The fluid mount of claim 3 wherein the piston connector is encircled by the second cylinder.

6. (Canceled)

7. (Currently Amended) The fluid mount of claim ~~[[6]]~~ 1 wherein the first chamber is in fluid communication with the second chamber.

8. (Canceled)

9. (Canceled)

10. (Currently Amended) The fluid mount of claim ~~8~~ further comprising a 1 wherein the control system that adjusts the pressure inside at least one of the chambers first chamber and the second chamber.

11. (Original) The fluid mount of claim 1 wherein the second subsystem is positioned directly above the first subsystem.

12. (Original) The fluid mount of claim 11 wherein the second subsystem is stacked on top of the first subsystem.

13. (Currently Amended) The fluid mount of claim 1 further comprising (i) a third ~~subassembly~~ subsystem that includes a third cylinder and a third piston moving within the third cylinder, the third piston cooperating with the third cylinder to define a third chamber, and (ii) a piston connector that couples the first piston, the second piston and the third piston together so that the pistons move concurrently, and (iii) a second intermediate chamber positioned between the second chamber and the third chamber, wherein the control system adjusts a pressure inside at least one of the intermediate chamber and the second intermediate chamber to be below atmospheric pressure.

14. (Original) The fluid mount of claim 13 wherein the third piston moves along a third axis that is substantially coaxial with the first axis and the second axis.

15. (Original) An isolation system including the fluid mount of claim 1.

16. (Original) An exposure apparatus including an apparatus frame and the fluid mount of claim 1 securing the apparatus frame to a mounting base.

17-32. (Canceled)

33. (Currently Amended) A method for making a fluid mount, the method comprising the steps of:

providing a first subsystem including a first cylinder and a first piston, the first piston moving within the first cylinder;

providing a second subsystem including a second cylinder and a second piston, the second piston moving within the second cylinder; and

coupling the first piston and to the second piston with a piston connector so that the first piston and the second piston move substantially concurrently;

positioning the second subsystem directly on top of the first subsystem;

providing an intermediate chamber between the first subsystem and the second subsystem; and

providing a control system that is connected to the intermediate chamber and actively adjusts a pressure inside the intermediate chamber to be below the lower one of a pressure inside the first subsystem and a pressure inside the second subsystem.

34. (Original) The method of claim 33 wherein the first piston moves along a first axis and the second piston moves along a second axis and further comprising the step of positioning the second subsystem relative to the first subsystem so that the second axis is substantially coaxial with the first axis.

35. (Canceled)

36. (Canceled)

37. (Currently Amended) The method of claim 33 further comprising steps of (i) providing a third ~~subassembly~~ subsystem that includes a third cylinder and a third piston moving within the third cylinder, and (ii) coupling the first piston, the second piston and the third piston together with a piston connector so that the pistons move concurrently.

38. (Currently Amended) The method of claim 37 wherein the first piston moves along a third axis and further comprising the step of positioning the third subsystem relative to the first subsystem and the second subsystem so that the third axis is substantially coaxial with the first ~~axial~~ axis and the second axis.

39. (Original) A method for making an isolation system including the step of providing a fluid mount made in accordance with claim 33.

40. (Original) A method for making an exposure apparatus including the steps of providing an apparatus frame and securing the apparatus frame to a mounting base with a fluid mount made in accordance with claim 33.

41. (Original) A method of making a wafer utilizing the exposure apparatus made by the method of claim 40.

42. (Original) A method of making a device including at least an exposure process, wherein the exposure process utilizes the exposure apparatus made by the method of claim 40.

43. (Currently Amended) A method for supporting a load comprising the steps of:

providing a first subsystem including a first cylinder and a first piston,

the first piston moving within the first cylinder along a first axis;

providing a second subsystem including a second cylinder and a second piston, the second piston moving within the second cylinder along a second axis that is substantially coaxial with the first axis;

providing an intermediate chamber between the first subsystem and the second subsystem;

controlling the pressure of at least one of the subsystems and actively adjusting a pressure inside the intermediate chamber to be below the lower of a pressure inside the first subsystem and a pressure inside the second subsystem;

connecting the first piston with the load; and

connecting the second piston with the load.

44. (Canceled)

45. (Currently Amended) The method of claim ~~[[44]]~~ 43 wherein the step of controlling the pressure of at least one of the subsystems includes the step of controlling the pressure of each subsystem independently.

46. (New) The method of claim 43 wherein the step of controlling the pressure includes the step of adjusting the pressure inside the intermediate chamber to be below atmospheric pressure.

47. (New) The fluid mount of claim 1 wherein the control system adjusts the pressure inside the intermediate chamber to be below atmospheric pressure.

48. (New) The method of claim 33 wherein the control system adjusts the pressure inside the intermediate chamber to be below atmospheric pressure.

49. (New) A fluid mount comprising:

a first subsystem including a first cylinder and a first piston, the first piston

moving within the first cylinder along a first axis;

a second subsystem including a second cylinder and a second piston, the second piston moving within the second cylinder along a second axis that is substantially coaxial with the first axis;

a cylinder connector that holds the first cylinder and the second cylinder, the cylinder connector lining up the first cylinder and the second cylinder along the first axis; and

a piston connector that couples the first piston and the second piston, the piston connector extending around the second cylinder.

50. (New) The fluid mount of claim 49 wherein the first piston cooperates with the first cylinder to define a first chamber and wherein the second piston cooperates with the second cylinder to define a second chamber.

51. (New) The fluid mount of claim 50 wherein the first chamber is in fluid communication with the second chamber.

52. (New) The fluid mount of claim 50 further comprising a control system that is connected to at least one of the subsystems and adjusts a pressure inside at least one of the chambers.

53. (New) A fluid mount comprising:

a first subsystem including a first cylinder, a first piston and a first seal, the first piston moving within the first cylinder, the first seal being fixedly secured to the first cylinder and the first piston; and

a second subsystem including a second cylinder, a second piston and a second seal, the second piston moving within the second cylinder, the second seal being fixedly secured to the second cylinder and the second piston, wherein the second piston moves concurrently with the first piston.

54. (New) The fluid mount of claim 53 wherein the first subsystem further includes a first clamp that fixedly secures the first seal to the first cylinder and wherein the second subsystem further includes a second clamp that fixedly secures the second seal to the second cylinder.

55. (New) The fluid mount of claim 53 further comprising a piston connector that couples the first piston to the second piston so that the first piston and the second piston move concurrently.

56. (New) The fluid mount of claim 53 wherein the first piston cooperates with the first cylinder to define a first chamber and wherein the second piston cooperates with the second cylinder to define a second chamber.

57. (New) The fluid mount of claim 56 further comprising an intermediate chamber positioned between the first chamber and the second chamber, and a control system that adjusts a pressure inside the intermediate chamber to be below the lower one of a pressure inside the first subsystem and a pressure inside the second subsystem.

58. (New) The fluid mount of claim 53 further comprising (i) a third subsystem that includes a third cylinder, a third piston and a third seal, the third piston moving within the third cylinder, the third seal being fixedly secured to the third cylinder and the third piston, and (ii) a piston connector that couples the first piston, the second piston and the third piston together so that the pistons move concurrently.

59. (New) An isolation system including the fluid mount of claim 53.

60. (New) An exposure apparatus including an apparatus frame and the fluid mount of claim 53 securing the apparatus frame to a mounting base.

61. (New) A fluid mount comprising:

a first subsystem including a first cylinder and a first piston, the first piston moving within the first cylinder and cooperating with the first cylinder to define a first chamber;

a second subsystem including a second cylinder and a second piston, the second piston moving within the second cylinder and cooperating with the second cylinder to define a second chamber;

an intermediate chamber positioned between the first chamber and the second chamber; and

a control system that actively and concurrently adjusts a pressure inside each of the first chamber, the second chamber and the intermediate chamber.

62. (New) The fluid mount of claim 61 further comprising a piston connector that couples the first piston to the second piston so that the first piston and the second piston move concurrently.

63. (New) The fluid mount of claim 61 further comprising (i) a third subsystem that includes a third cylinder and a third piston, the third piston moving within the third cylinder and cooperating with the third cylinder to define a third chamber, and (ii) a piston connector that couples the first piston, the second piston and the third piston together so that the pistons move concurrently.

64. (New) The fluid mount of claim 63 further comprising a second intermediate chamber positioned between the second chamber and the third chamber, wherein the control system actively and concurrently adjusts the pressure inside each of the first chamber, the second chamber, the third chamber, the intermediate chamber and the second intermediate chamber.